



# Vertical Electro-Polishing at CEA Saclay: update April 16th 2013









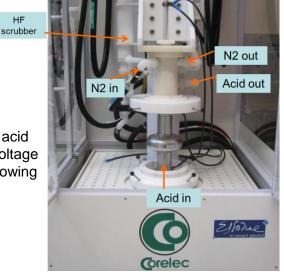
## **Overview**



- Circulating acid ٠
- Constant voltage

HF

Nitrogen blowing





5 Fermilab TB9RI025 cavity Prior to VEP

- VEP of 1Cell and 9Cell cavities
- Focus on parameters: low voltage ( $\sim 6V$ ) high acid flow (25L/min) -
  - Improved degassing  $(H_2, O_2)$ 0
  - Lower heating 0
- Four 1-Cell cavities and 1 nine-cell cavity prepared by VEP -
- But delay in results: Field Emission problems (cleanroom's water)



### Eacc > 41 MV/m on 1Cell Cavity with Parameters:

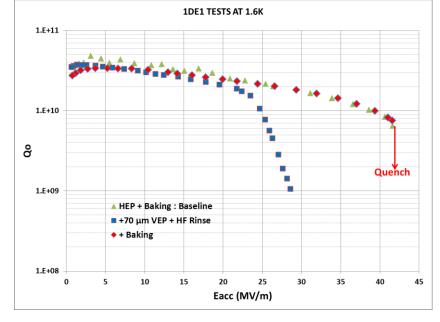
#### Low Voltage – High Acid Flow



- DESY
- 1DE1: Horizontal EP + 70 µm VEP
- Parameters: 6V & >24L/min
- Bright and smooth surface
- Performance before/after baking similar to HEP
- High gradient maintained after VEP



### 1DE1 after HEP + 70 µm VEP



Aspects to improve:

- Low removal rate at 19°C: 0.2µm/min
- asymmetry: removal rate higher in the upper part of the cell (x 3)

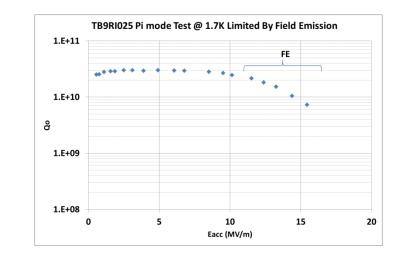






Cavities VEP'ed at 6V & 25L/min:

- 1AC3 (34MV/m at previous test) + 70 µm VEP + Baking
- TB9RI025: (HEP + 60 µm VEP) last test impacted by Field Emission :



 $\rightarrow$  additional HF rinsing + HPR + assembly. Under testing...